

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Akihisa HONGO et al.

Serial No. 09/842,650

Filed April 27, 2001



: Confirmation No. 7681

: Docket No. 2001_0519A

: Group Art Unit 1763

: Examiner S. Macarthur

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AMENDMENT

Commissioner for Patents
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Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
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Sir:

In response to the Office Action of August 1, 2003, the period for response to which having been extended by two months to January 1, 2004, please amend the above-identified U.S. Patent application as follows:

01/06/2004 CCHAU1 00000173 09842650

03 FC:1202

360.00 OP